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Helicity-dependent THz emission induced by ultrafast spin photocurrent in nodal-line semimetal candidate Mg₃Bi₂

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Section 1: Sample preparation

The Mg₃Bi₂ thin fims were grown on sapphire substrates by using molecular beam epitaxy (MBE) in ultrahigh vacuum (UHV) chambers equipped with reflection high-energy electron diffraction (RHEED) system. The sapphire substrate was heated to 800°C for 2 hours to remove contaminants. High-purity Mg and Bi were evaporated by standard Knudsen cells. The base pressure for the MBE system was less than 1×10^{-10} mBar and the growing pressure for the Mg₃Bi₂ thin films was maintained at less than 3×10^{-9} mBar. The Mg and Bi effusion cell temperatures were selected so that the fluxing ratio Mg/Bi was more than 5. The substrate temperature was maintained at 280–380°C throughout the growth. The thickness of the Mg₃Bi₂ films in this work is ~90 nm. Finally, Se was deposited on Mg₃Bi₂ surface to prevent the film from oxidation and pollution.



Fig. S1 | Schematic of the THz emission spectroscopy system.



Fig. S2 | The coefficients C, L₁, L₂ and D are extracted from the fit in Fig. 3(d). The solid line is a fit to Eq. (2).

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Fig. S3 | (a) The α -dependent terahertz emission in E_{γ} direction. (b) The coefficients extracted from the fit in Fig. S3a.

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